



UNITED STATES PATENT AND TRADEMARK OFFICE

UNITED STATES DEPARTMENT OF COMMERCE
 United States Patent and Trademark Office
 Address: COMMISSIONER FOR PATENTS
 P.O. Box 1450
 Alexandria, Virginia 22313-1450
 www.uspto.gov



Bib Data Sheet

CONFIRMATION NO. 1783

SERIAL NUMBER 10/532,459	FILING OR 371(c) DATE 11/02/2005 RULE	CLASS 438	GROUP ART UNIT 2812	ATTORNEY DOCKET NO. AB-1432 US	
APPLICANTS Hyun-Jae Kim, Seongnam-city, KOREA, REPUBLIC OF; Myung-Koo Kang, Seoul, KOREA, REPUBLIC OF;					
** CONTINUING DATA ***** <i>NA</i> This application is a 371 of PCT/KR03/02212 10/21/2003					
** FOREIGN APPLICATIONS ***** REPUBLIC OF KOREA 10-2002-0064511 10/22/2002 <i>NA</i>					
Foreign Priority claimed <input checked="" type="checkbox"/> yes <input type="checkbox"/> no 35 USC 119 (a-d) conditions met <input type="checkbox"/> yes <input checked="" type="checkbox"/> no <input type="checkbox"/> Met after Allowance Verified and Acknowledged <i>[Signature]</i> Examiner's Signature Initials		STATE OR COUNTRY KOREA, REPUBLIC OF	SHEETS DRAWING 5	TOTAL CLAIMS 7	INDEPENDENT CLAIMS 3
ADDRESS 32605					
TITLE Method of polycrystallization, method of manufacturing polysilicon thin film transistor, and laser irradiation device therefor					
FILING FEE RECEIVED 1030	FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT No. _____ for following:		<input type="checkbox"/> All Fees <input type="checkbox"/> 1.16 Fees (Filing) <input type="checkbox"/> 1.17 Fees (Processing Ext. of time) <input type="checkbox"/> 1.18 Fees (Issue) <input type="checkbox"/> Other _____ <input type="checkbox"/> Credit		